

**Form PTO-1449**  
**Patent and Trade**

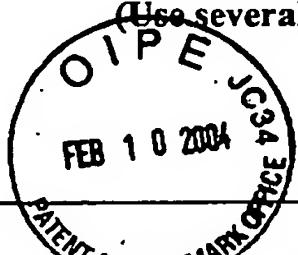
## **U.S. Department of Commerce**

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566.38683CX1

Serial No.  
10/042,271

## **INFORMATION DISCLOSURE CITATION BY APPLICANT**

(Use several sheets if necessary)



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Applicant  
YOSHIDA, ET AL.

**Filing Date** 01/11/02

## **U.S. PATENT DOCUMENTS**

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## FOREIGN PATENT DOCUMENTS

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

SLW	<p>1. 1996 Proceedings First International Chemical-Mechanical Polish (C.M.P.) for VLSI/ULSI MULTILEVEL INTERCONNECTION CONFERENCE (CMP-MIC) "Selective CMP of Organic Sog for Low Parasitic Capacitance Quarter-Micron Multilevel Interconnections", By: Yoshio HOMA, et al. Feb. 22-23, 1996</p>

**EXAMINER**

**DATE CONSIDERED**

Shantel Mestrom

9/30/04